THE INVENTION CLAIMED IS

 ${\bf 1.} \quad {\bf A} \ {\bf method} \ {\bf of} \ {\bf removing} \ {\bf a} \ {\bf metal} \ {\bf from} \ {\bf a} \ {\bf substrate}$ comprising:

providing a substrate having metal formed

thereon;

contacting the substrate with a reactive surface comprising a first complexing agent; and removing metal particles from the substrate via bonding between the metal and the first complexing agent.

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- 2. The method of claim 1 wherein providing a substrate comprises providing a semiconductor substrate having a metal formed thereon.
- 3. The method of claim 1 wherein providing a substrate having a metal formed thereon comprises providing a substrate having a metal compound formed thereon.
- 4. The method of claim 3 wherein the metal compound comprises a metal oxide.
- 5. The method of claim 1 further comprising:
 cleaning the reactive surface via applying a second
 complexing agent that is stronger than the first complexing
 agent to thereby remove metal particles from the reactive
 surface.
- The method of claim 5 wherein cleaning the reactive surface via applying a second complexing agent
 comprises cleaning the reactive surface via applying a second complexing agent comprising ammonium hydroxide, ammonia or carboxylic acid.

- 7. The method of claim 1 further comprising: cleaning the reactive surface by electrically biasing the reactive surface.
- 5 8. The method of claim 7 wherein electrically biasing the reactive surface comprises:

 $\label{eq:placing} \mbox{placing a metal disk on the reactive surface;}$ and

applying a bias between the metal disk and the 10 reactive surface.

- The method of claim 1 further comprising: cleaning the reactive surface with sulfuric acid.
- The method of claim 1 wherein contacting the substrate with a reactive surface comprising a first complexing agent comprises contacting the substrate with a
 reactive surface comprising a first complexing agent comprising a bispicolylamine functionality, an amine, a carboxilate, a chloride or a sulfonate.
- 12. The method of claim 1 wherein the first 30 complexing agent is solid material attached to the reactive surface.

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- 13. The method of claim 12 wherein the complexing agent is attached to the reactive surface by one of bonding, grafting and blending.
 - 14. A brush apparatus comprising:

a scrubber brush having:

 $\hbox{a surface adapted to contact a surface of} \\ \hbox{a substrate to be scrubbed; and} \\$

a complexing agent coupled to the

- scrubber brush surface, the complexing agent adapted to bond to metal particles.
 - 15. The apparatus of claim 14 wherein the complexing agent is adapted to bond to a metal compound.
 - $\mbox{16.} \quad \mbox{The apparatus of claim 15 wherein the metal compound is a metal oxide.}$
 - 17. The apparatus of claim 14 wherein the complexing agent is a solid material attached to the scrubber brush surface.
 - 18. The apparatus of claim 17 wherein the complexing agent is attached to the scrubber brush surface by one of bonding, grafting and blending.
 - 19. An apparatus comprising:

a scrubber brush comprised of a homogeneous material comprising a complexing agent adapted to bond to metal particles, and having a surface adapted to contact a surface of a substrate to be scrubbed.

20. A scrubber comprising:

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a substrate support adapted to support a substrate:

a brush coupled so as to contact a substrate supported by the substrate support, the brush having:

a surface adapted to contact a surface of a substrate to be scrubbed; and

a complexing agent coupled to the scrubber brush surface, the complexing agent adapted to bond to metal particles; and

10 a mechanism adapted to generate relative movement between the substrate and the brush apparatus.

 $\mbox{21.} \quad \mbox{A method of regenerating a scrubber brush,} \\ \mbox{comprising:} \\$

providing a scrubber brush having a reactive surface comprising a first complexing agent to which metal particles have bonded; and

cleaning the reactive surface by applying a second complexing agent that is stronger than the first complexing agent to thereby remove at least some of the metal particles from the reactive surface.

- 22. The method of claim 21 wherein the second complexing agent is ammonium hydroxide, ammonia or carboxylic acid.
 - 23. A method of regenerating a polishing pad, comprising:

providing a polishing pad having a reactive surface comprising a first complexing agent to which metal particles have bonded; and

cleaning the reactive surface by applying a second complexing agent that is stronger than the first

complexing agent to thereby remove at least some of the metal particles from the reactive surface.

- 24. The method of claim 23 wherein the second 5 complexing agent is ammonium hydroxide, ammonia or carboxylic acid.
 - $\begin{tabular}{ll} 25. & A method of regenerating a polishing pad, \\ comprising: \\ \end{tabular}$
- providing a polishing pad having a reactive surface comprising a complexing agent to which metal particles have bonded; and

removing a layer of the reactive surface with a conditioning head to expose a new layer of reactive surface.

 $$\it 26$$. A method of regenerating a scrubber brush, comprising:

providing a scrubber brush having a reactive surface comprising a first complexing agent to which metal particles have bonded; and

cleaning the reactive surface by electrically biasing the reactive surface.

25 27. The method of claim 26 wherein electrically biasing the reactive surface comprises:

 $\label{eq:placing} \mbox{placing a conductive material on the reactive} \\ \mbox{surface; and} \\$

applying a bias between the conductive 30 material and the reactive surface.

 $\ \ \,$ 28. A method of regenerating a polishing pad, comprising:

providing a polishing pad having a reactive surface comprising a first complexing agent to which metal particles have bonded; and

cleaning the reactive surface by electrically 5 biasing the reactive surface.

 $\ensuremath{\mbox{29}}\xspace$. The method of claim 28 wherein applying a bias comprises:

placing a conductive material on the reactive

10 surface; and

applying a bias between the conductive material and the reactive surface.

- 30. The method of claim 29 wherein the conductive material is part of a conditioning head.
- 31. A method of regenerating a scrubber brush, comprising:

providing a scrubber brush having a reactive surface comprising a first complexing agent to which metal particles have bonded; and

cleaning the reactive surface with a strong acid to thereby remove at least some of the metal particles from the reactive surface.

32. The method of claim 31 wherein the strong acid is sulfuric acid.

33 . A method of regenerating a polishing pad,

30 comprising:

providing a polishing pad having a reactive surface comprising a first complexing agent to which metal particles have bonded; and cleaning the reactive surface with a strong acid to thereby remove at least some of the metal particles from the reactive surface.